

5.0 credits	30.0 h + 30.0 h	1q
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Teacher(s) :	Flandre Denis ; Pardoen Thomas ; Francis Laurent (coordinator) ; Raskin Jean-Pierre ;
Language :	Anglais
Place of the course	Louvain-la-Neuve
Inline resources:	http://icampus.uclouvain.be/claroline/course/index.php?cid=ELEC2895
Main themes :	This cursus is part of the MEMS & mp; NEMS, Micro and Nanotechnology ELEC options. LELEC2895 is focused on the understanding and the design of micro-electromechanical devices (MEMS), on transducers (sensors, actuators) made using micro and nanofabrication technologies, to their co-integration with integrated circuits (IC), to their multiphysics simulation and characterisation, to their reliability and their interconnect.
Aims :	<p>a. Contribution of the activity to the learning outcomes of the program 1 (1.1, 1.2, 1.3), 2 (2.1, 2.2, 2.3, 2.4, 2.5), 3 (3.1, 3.2, 3.3), 4 (4.2, 4.3, 4.4), 5 (5.1, 5.2, 5.3, 5.4, 5.5, 5.6), 6 (6.1, 6.3, 6.4)</p> <p>b. After this cursus, the student will be able to:</p> <p>-- Describe the transduction principles and scaling effects -- Understand specifications for a MEMS -- Design MEMS and NEMS and use multiphysics simulation softwares and tools -- Identify electronic circuits adapted to MEMS and NEMS -- Identify fabrication techniques required to make such devices -- Analyse the reliability of miniaturised devices -- Present (report) and defend (slides) the results of a group project (with 2 to 4 students) <i>The contribution of this Teaching Unit to the development and command of the skills and learning outcomes of the programme(s) can be accessed at the end of this sheet, in the section entitled "Programmes/courses offering this Teaching Unit".</i></p>
Evaluation methods :	The project evaluation is based on the style and content of a written report and an oral presentation made by group. The exam is an open book format.
Teaching methods :	The course is organised as following 8 sessions of theoretical lectures 3 sessions of exercices 2 tutorial sessions to become acquainted with the software required for the project
Content :	1. MEMS design methodology 2. Scale effects and transduction principles 3. Sensors and actuators: electrical, mechanical, thermal, optical, (bio)chemical, etc... 4. Fabrication processes 5. MEMS and CMOS technology circuits co-integration 6. Interconnections and packaging 7. Multiphysics simulations and characterizations
Bibliography :	Supports -- Slides available on iCampus -- Reference books available at the library BST
Other infos :	LELEC2560 Micro and Nanofabrication Techniques is a desirable prerequisite. Basic knowledge of electronics, solid-state physics, materials science and chemistry is an advantage.

<p>Cycle and year of study :</p>	<p>> Master [120] in Electrical Engineering > Master [120] in Physical Engineering > Master [120] in Chemical and Materials Engineering > Master [120] in Electro-mechanical Engineering</p>
<p>Faculty or entity in charge:</p>	<p>ELEC</p>